

2.4 μm cutoff wavelength AlGaAsSb/InGaAsSb phototransistors

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We report the first AlGaAsSb/InGaAsSb phototransistors with a cutoff wavelength (50% of peak responsivity) of 2.4 μm operating in a broad range of temperatures. These devices are also the first AlGaAsSb/InGaAsSb heterojunction phototransistors (HPT) grown by molecular beam epitaxy (MBE). This work is a continuation of a preceding study, which was carried out using LPE (liquid phase epitaxy)-grown AlGaAsSb/InGaAsSb/GaSb heterostructures. Although the LPE-related work resulted in the fabrication of an HPT with excellent parameters [1-4], the room temperature cutoff wavelength of these devices ($\approx 2.15 \mu\text{m}$) was determined by fundamental limitations implied by the close-to-equilibrium growth from Al-In-Ga-As-Sb melts. As the MBE technique is free from the above limitations, AlGaAsSb/InGaAsSb/GaSb heterostructures for HPT with a narrower bandgap of the InGaAsSb base and collector – and hence sensitivity at longer wavelengths (λ) – were grown in this work. Moreover, MBE – compared to LPE – provides better control over doping levels, composition and width of the AlGaAsSb and InGaAsSb layers, compositional and doping profiles, especially with regard to abrupt heterojunctions. The new MBE-grown HPT exhibited both high responsivity R (up to 2334 A/W for $\lambda = 2.05 \mu\text{m}$ at -20°C .) and specific detectivity D^* (up to $2.1 \times 10^{11} \text{cmHz}^{1/2}/\text{W}$ for $\lambda = 2.05 \mu\text{m}$ at -20°C).

Introduction: The spectral range 2.0 – 2.4 μm wavelength is of great interest for several important applications, including profiling of atmospheric CO_2 using light detection and ranging (LIDAR) techniques [5,6], and non-invasive monitoring of blood glucose using absorption spectroscopy [7]. In this work, the MBE-grown AlGaAsSb/InGaAsSb solid alloys are used for the first time to fabricate HPT providing a high internal gain at the wavelength as long as 2.4 μm . Moreover, the new high-gain phototransistors operate at low bias (less than 1.5 volts).

Experimental: The HPT mesa structure (Fig.1) fabricated and studied in this work is composed of $\text{Al}_{0.25}\text{Ga}_{0.75}\text{As}_{0.02}\text{Sb}_{0.98}$ and $\text{In}_{0.18}\text{Ga}_{0.82}\text{As}_{0.17}\text{Sb}_{0.83}$ layers with room-temperature bandgaps of $E_g \approx 1.0$ eV and $E_g \approx 0.54$ eV, respectively. The layers are lattice-matched to a GaSb substrate and were grown at 500°C on an n^+ -GaSb (001) substrate using a Riber 32 solid source MBE. A valved cracker source for arsenic (As_4) and a conventional effusion source for antimony (Sb_4) were used. The growth started with a 0.15 μm -thick n^+ -GaSb buffer layer and was completed with a 0.1 μm -thick n^+ -GaSb contact layer doped with Te. The HPT structure includes a 0.5 μm -thick n-type AlGaAsSb emitter, 0.8 μm -thick p-type composite base consisting of AlGaAsSb (0.3 μm) and InGaAsSb (0.5 μm) layers, and a 1.5 μm - thick n-type InGaAsSb collector. Mesa HPT with a 400- μm diameter total area and a 300- μm diameter active area were defined using photolithography and wet chemical etching. A backside planar and frontside annular ohmic contact (together with a bonding pad) were deposited by electron-beam evaporation of Au/Ge. A polyimide coating (HD Microsystems PI-2723 photodefinable polyimide resin) was spun on the front of the device. The polyimide served several functions including planarization of the top surface, mesa isolation, and edge passivation.

After dicing, 1-mm² pieces with a single device in the middle of each square were mounted to TO-18 headers using silver conducting epoxy and wire-bonded. No antireflection coatings were applied.

Results: Spectral response, dark current and noise measurements were performed for MBE-grown phototransistors. Measurements of spectral response were carried out using the equipment described in Ref. [4]. Fig.2 shows spectral response of an AlGaAsSb/InGaAsSb HPT at the specified bias voltage and +20°C. As can be seen in Fig.2, responsivity R rapidly increases with applied bias voltage and at 1.4 V reaches 1128 A/W for $\lambda = 2.04 - 2.08\mu\text{m}$. Even higher values of R (up to 2334 A/W) were measured at -20°C at 1.4 V for $\lambda = 2.05 \mu\text{m}$. Fig. 3 shows responsivity R of an AlGaAsSb/InGaAsSb HPT at $\lambda = 2.05 \mu\text{m}$ vs. bias voltage at temperatures from -20°C to +100°C. One can distinguish two parts of the graph: at very low voltage (< 1V) higher R was measured at higher temperatures, while at higher voltages the opposite dependence was observed. This complicated behavior can be explained by temperature dependencies of minority-carrier (electrons) diffusion length in the base, and by the as-yet-unexplored temperature-sensitive band discontinuities of AlGaAsSb/InGaAsSb heterojunctions, which can affect the minority carrier injection at the emitter-base junction and consequently the gain of the HPT. On the other hand, the dark current and hence the noise current I_n of the HPT are also dependent on applied voltage and temperature. All the above dependencies are considered in specific detectivity D^* , which is one of the main figures of merit for any photodetector:

$$D^*(T,V) = R(T,V) \cdot \sqrt{A}/I_n(T,V), \quad (1)$$

where A is the detector area.

Fig. 4 exhibits a 2.05- μm detectivity D^* of an AlGaAsSb/InGaAsSb HPT at -20°C and $+20^\circ\text{C}$ vs. bias voltage. D^* value as high as $2.1 \times 10^{11} \text{ cmHz}^{1/2}/\text{W}$ was determined at -20°C and 1.3 V.

We believe the significant performance levels achieved with the first MBE-grown HPT structures bode well for the AlGaAsSb/InGaAsSb HPT approach to mid-infrared detectors, as well as for the materials and device fabrication technology described here. Moreover, we believe there is much room for further improvements in both R and D^* of the AlGaAsSb/InGaAsSb HPT through continued optimization of the design and fabrication.

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Figure captions:

Figure 1. Structure (cross-section) of the fabricated AlGaAsSb/InGaAsSb HPT

Figure 2. Spectral response of an AlGaAsSb/InGaAsSb HPT at the specified bias voltage and +20°C

Figure 3. Responsivity of an AlGaAsSb/InGaAsSb HPT at $\lambda = 2.05 \mu\text{m}$ vs. bias voltage at specified temperatures

Figure 4. A 2.05- μm detectivity D^* of an AlGaAsSb/InGaAsSb HPT at -20°C and $+20^\circ\text{C}$ vs. bias voltage

Figure 1

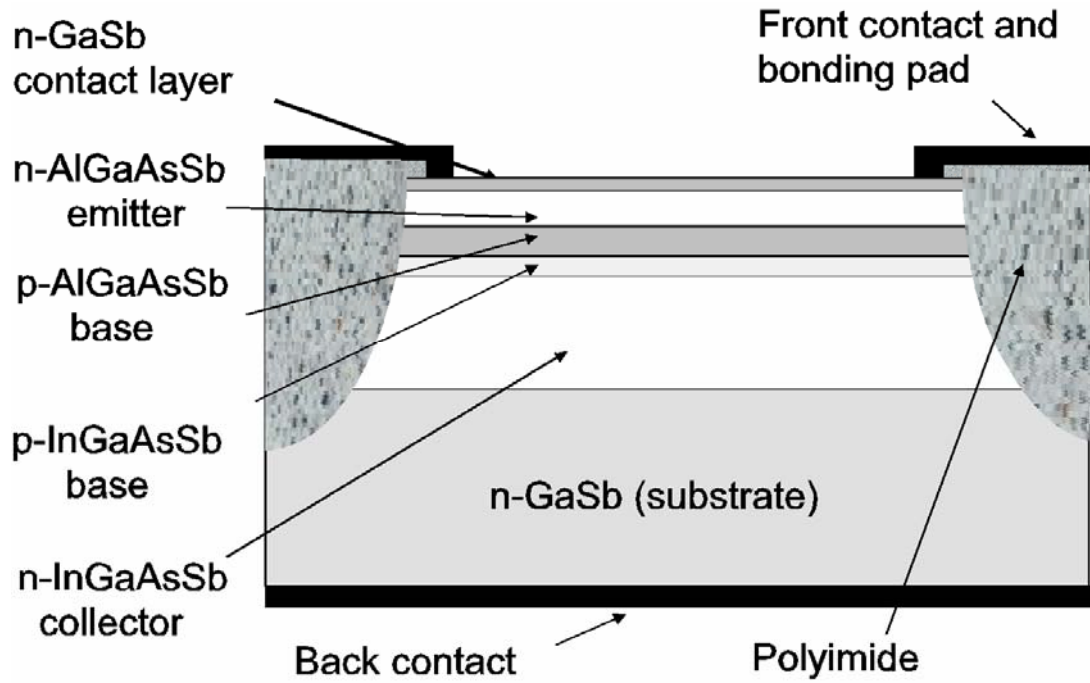


Figure 2

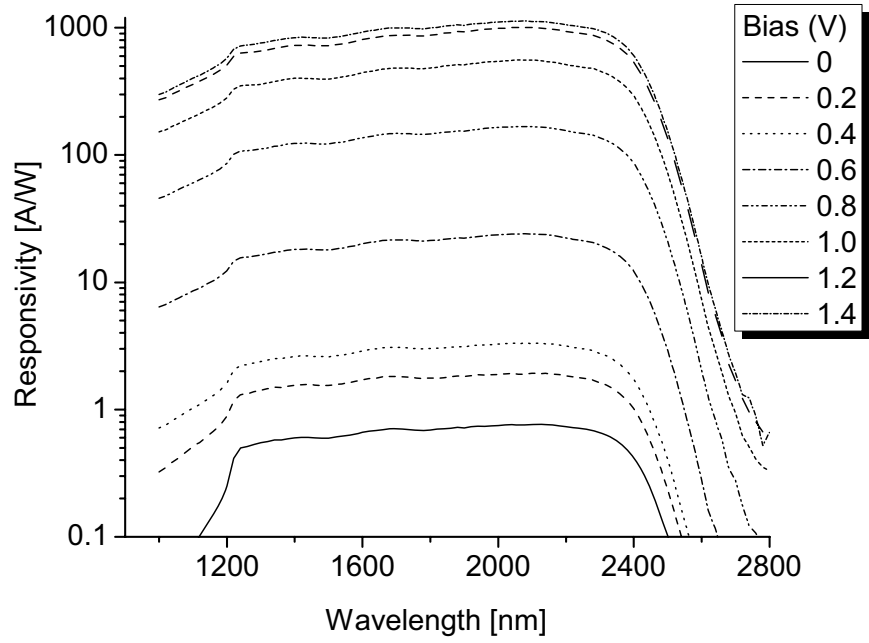


Figure 3

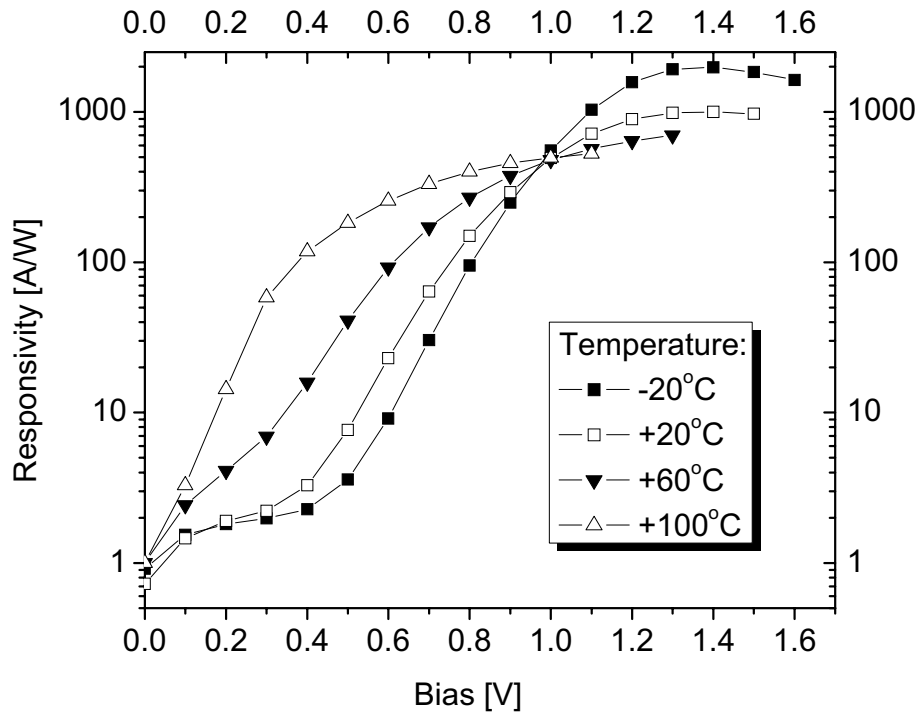


Figure 4

